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Substitute for Form 1449/APTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Complete if Known	
				Application Number	Unknown
				Filing Date	Herewith
				First Named Inventor	Wan-Thai, Hsu, et al.
				Group Art Unit	Unknown
				Examiner Name	Unknown
Sheet	1	of	2	Attorney Docket Number	UOM 0210 PUSP 1

U.S. PATENT DOCUMENTS						
Examiner Initials ¹	Cite No. ¹	U.S. PATENT DOCUMENT		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
M		5,082,242		Bonne et al.	01-21-1992	
		5,455,547		Lin, et al.	10-03-1995	
		5,491,604		Nguyen et al.	02-13-1996	
		5,537,083		Lin, et al.	07-16-1996	
		5,589,082		Lin, et al.	12-31-1996	
		5,640,133		MacDonald et al.	06-17-1997	
		5,839,062		Nguyen et al.	11-17-1998	
		5,914,553		Adams et al.	06-22-1999	
		5,955,932		Nguyen et al.	09-21-1999	
		6,167,757		Yazdi et al.	01-02-2001	
		6,236,281		Nguyen et al.	05-22-2001	
		6,249,073		Nguyen et al.	06-19-2001	
		6,204,737		Ella, Juha	03-20-2001	
		6,265,806		Suzuki, Kenichiro	07-24-2001	
		6,305,779		Capurso et al.	10-23-2001	
		6,316,827		Asano et al.	11-13-2001	
		6,393,913		Dyck et al.	07-28-2002	
		6,448,622	B1	Franke et al.	09-10-2002	




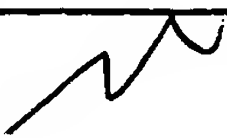
FOREIGN PATENT DOCUMENTS								
Examiner Initials ¹	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office ³	Number ⁴	Kind Code ⁵ (if known)				



Examiner Signature	<i>H. Jey Jann</i>	Date Considered	<i>7/8/04</i>
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¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

Substitute for Form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete If Known	
				Application Number	Unknown
				Filing Date	Herewith
				First Named Inventor	Wan-Thai Hsu, et al.
				Group Art Unit	Unknown
				Examiner Name	Unknown
Sheet	2	of	2	Attorney Docket Number	UOM 0210 PUSP 1
OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS					
Examiner Initials [*]	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			T ²
		HSU, WAN-THAI, ET AL., A Sub-Micron Capacitive Gap Process For Multiple-Metal-Electrode Lateral Micromechanical Resonators, Technical Digest, IEEE Int. Micro Electromechanical Systems Conf., Interlake, Switzerland, January 21-25, 2001, pp. 349-352.			
		HSU, WAN-THAI, ET AL., Mechanically Temperature-Compensated Flexural-Mode Micromechanical Resonators, Technical Digest, IEEE Int. Electron Devices Meeting, San Francisco, California, Dec. 11-13, 2000, pp. 399-402.			
		CLARK, JOHN R., ET AL., High-Q VHF Micromechanical Contour-Mode Disk Resonators, Technical Digest, IEEE Int. Electron Devices Meeting, San Francisco, California, December 11-13, 2000, pp. 493-496.			
		CLARK, JOHN R., ET AL., Measurement Techniques For Capacitively-Transduced VHF-to-UHF Micromechanical Resonators, Digest of Technical Papers, the 11 th Int. Conf. on Solid-State Sensors & Actuators, Munich, Germany, June 10-14, 2001, pp. 1118-1121.			
		C. T.-C. NGUYEN, "Micromachining technologies for miniaturized communication devices," Proceedings of SPIE: Micromachining and Microfabrication, Sept. 20-22, 1998, pgs. 24-38			
		T. HIRANO et al., "Design, Fabrication, and Operation of Submicron Gap Comb-Drive Microactuators," Journal of Microelectromechanical Systems, March 1992, No. 1, pgs. 52-59			
		J.R. TUCKER et al., "Nanoscale FETs and STM Lithography," University of Illinois, 1995, pgs. 425-434			
		C. T.-C. Nguyen, "High-Q Micromechanical Oscillators and Filters For Communications," Int'l Symposium on Circuits and Systems, June 9-12, 1997, pgs. 2825-2828			
		K. TANAKA, "Nanotechnology towards the 21 st Century," Thin Solid Films, 1999, pgs. 120-125			

Examiner Signature		Date Considered	
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